

**Notice of References Cited**

Application/Control No.

08/636,069

Applicant(s)/Patent Under  
Reexamination  
SANDHU ET AL.

Examiner

Erik Kielin

Art Unit

2813

Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-			
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	D	US-			
	E	US-			
	F	US-			
	G	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

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	N	EP 0 562 625 A2 /	03-1993	EPO	Imai et al.	--
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**NON-PATENT DOCUMENTS**

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	U	Pierson, Handbook of Chemical Vapor Deposition, Noyes Publications: Park Ridge, New Jersey, 1992, pp.26-27.
	V	Translation of JP 2-050966 (Hisamune, Yoshiaki).
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	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.